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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Miller et al. Group: 2834  
Serial No.: 09/964,922 Paper No.:  
Filed: 09/26/2001 Examiner: M. Budd  
For: Apparatus to position a microelectromechanical platform

**AMENDMENT**

Assistant Commissioner for Patents  
Washington, DC 20231

Sir:

Applicants have carefully reviewed the Office Action mailed 11/18/02, submit the following in complete response thereto, and request reconsideration of the claims presented.

**IN THE CLAIMS**

Please cancel Claims 8 and 9.

Please amend Claims 1, 2, and 10-11 as follows:

1. (amended) A microelectromechanical positioner, comprising:  
a substrate;  
a moveable platform;

at least one linkage mechanism having a plurality of links, wherein the linkage mechanism is pivotably attached to the substrate by at least two anchor links and pivotably attached to the moveable platform by at least two platform links, and whereby the platform is constrained to exhibit substantially translational movement in a plane; and

at least one rotary actuator operatively connected to at least one anchor link to provide motion thereto.

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